Plasma dynamics of 1kHz repetitive laser ion source

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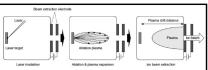


Introduction

Repetitive laser ion source

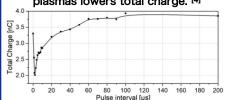
Laser ion source[1]

Compared to conventional ion sources, the plasma density is high. Therefore, high current ion beams can be easily generated.



Issues of repetitive operation using laser ion source

▶ Interaction between the generated
▶ Obstruction of ion plasmas lowers total charge. [4]



transport by particles remaining in a chamber.

It is necessary to measure the ablation plasma generated by the repetitive operation of a laser.

Repetitive operation

- Application
- · lon implantation[2]
- Spot scanning for medical accelerator[3]

Requirement

- High dose^[4]
- · High repetitive operation[5]

Purpose

Study on the effect of a high repetition rate operation of a repetitive laser ion source on ion production

- Generation of ablation plasmas with a 1 kHz repetitive laser
- Simultaneous measurement of impulse, ion current density, and drift velocity
 - Impulse: Pressure sensor · Ion current density : Faraday cup
 - Drift velocity: TOF measured with a Faraday cup
- Estimation of ion production efficiency

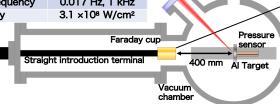
Experimental setup

Ablation plasma of Al is generated using a high repetition rate Nd:YAG Laser.

Time-resolved measurement of an impulse l ion current density J_{i} . and drift velocity $v_{\rm d}$

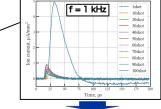
- · Ablation mass: ma
- Number of ions: M
- · Number of all particles: Nall
- · Ionization efficiency: η i

Experimental condition Pressure in a chamber 1.4 ~ 2.6 × 10-3 Pa Number of shot 100 shot Repetition frequency 0.017 Hz, 1 kHz Laser intensity



Nd:YAG Laser

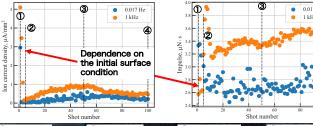
lon current density with TOF

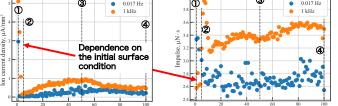


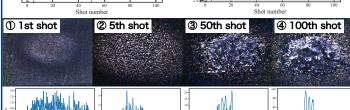
- Peak values of ion current density
- Drift velocity

Results and Discussion

Dependence of ion current density and impulse on shot number and repetition freq., surface condition of Al target

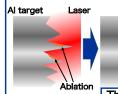






- For the repetitive operation from 0.017 Hz to 1 kHz, ion current
- The surface becomes rougher and rougher with each shot, and the raised area is up to about $90 \mu m$ by 100th shot.

and impulse are similar trend of repetition frequency.

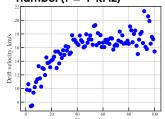


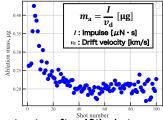
When this rough surface is irradiated with the laser, plasma is deposited on the rough surface.

The number of particles reaching the Faraday cup decreases.

The surface roughness affects ion production.

Dependence of drift velocity and ablation mass on shot number(f = 1 kHz)

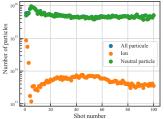


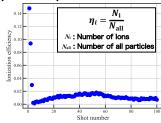


- v_d increases up to 40th shot, saturates after 40th shot.
- ma decreases up to 40th shot, remains constant after 40th shot.

The dependence of the ablation mass and drift velocity changed after the 40th shot. This may be due to the difference in surface composition and influence of the surface condition during laser irradiation.

Dependence of number of particles and ionization efficiency on shot number (f = 1 kHz)





- The generated plasma is composed of nearly neutral particle.
- ▶ 1~4 shot: Rapid decrease, 4~100 shot: Maximum at 58 shot

The dependence on the surface condition, the ionization efficiency decreases with irradiation to the same point.

Conclusion

- Until repetition frequency of 1 kHz, there is no effect of repetitive operation of the laser ion source.
- The mass and number of particles ejected from the Al target are affected by the surface roughness.
- Repetitive operation of the laser ion source roughen the target surface. > Ionization efficiency is almost constant 2 %
- [1] K.Takahashi et al.: J.Plasma Fusion Res 94, No.6, pp287-293(2018) [2] F.Belloni et al.: Proceedings of EPAC 2006, WECH181, pp2355-2357 [3] D.Trbojevic et al.: Proceedings of IPAC 2011, WEPS023, pp2541-2543 [4] H.Kashiwagi and K.Yamada: Rev. Sci. Instrum. 91, 033305 (2020) [5] T. Kanesue and S. Ikeda, et al.: Proceedings of IPAC2017, MOPIK053, pp638-640 (2017)